

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE


Applicant(s): **OKUDA, et al.**Application No.: **10/018,708**Filed: **Dec. 13, 2001****Title: Table of Wafer Polishing
Apparatus, Method for Polishing
Semiconductor Wafer, and Method for
Manufacturing Semiconductor Wafer**Attorney Docket No.:
P3P2000078US/2369NPGroup Art Unit: **3723**

Examiner:

RECEIVED
OCT 18 2002
TECHNOLOGY CENTER 3700Assistant Commissioner for Patents
Washington, D.C. 20231**POWER TO INSPECT/COPY**

Dear Sir:

Please permit **B. B. Landsdown** of **B's Business Service, Inc.**, to inspect the above-entitled application, and to make copies of any of the papers that she may desire.



Stephen G. Sullivan, Reg. No. 38,329
Sawyer Law Group LLP
Attorneys for Applicant
P. O. Box 51418
Palo Alto, CA 94303
(650) 493-4540Customer No. **29141**Date: **October 17, 2002**Power to Inspect
11/25/02
11649
RECEIVED
NOV 25 2002
TECHNOLOGY CENTER 3700